

What Is Claimed Is:

1. A method of fabricating a liquid crystal display device, comprising:
 - providing a first substrate;
 - forming an alignment layer on the first substrate using an ink jet method
 - to form a plurality of holes that expose portions of the first substrate; and
 - forming a spacer within each of the plurality of holes using the ink jet method.

2. The method according to claim 1, wherein the step of providing a first substrate, comprises:
 - forming gate lines and data lines arranged along transverse and longitudinal directions on a transparent substrate to define a plurality of pixel areas;
 - forming a thin film transistor at crossing points of the gate and data lines;
 - forming a passivation layer along an entire surface of the transparent substrate including the thin film transistor; and
 - forming a pixel electrode within each of the pixel areas.

3. The method according to claim 1, wherein the step of providing a first substrate comprises:

forming a black matrix on a transparent substrate;

forming a color filter on the black matrix; and

forming a common electrode on the color filter.

4. The method according to claim 1, wherein the step of forming an alignment layer includes an ink jet system.

5. The method according to claim 4, wherein the ink jet system comprises:

a nozzle dropping an amount of an alignment material onto a surface of the first substrate:

a plurality holes in the nozzle; and

an alignment material supplying unit for supplying the alignment material to the nozzle.

6. The method according to claim 5, wherein the amount of the alignment material dropped onto the surface of the first substrate is controlled by one of opening and closing the plurality of holes formed in the nozzle.

7. The method according to claim 5, wherein the alignment material is applied onto the surface of the first substrate by movement of the nozzle.
8. The method according to claim 1, wherein the spacers include an organic material.
9. The method according to claim 8, wherein the organic material includes a photoresist material.
10. The method according to claim 1, further comprising a step of dispensing liquid crystal material onto the first substrate.
11. A method of fabricating a liquid crystal display device, comprising:
 - providing a lower substrate upon which a thin film transistor is formed and an upper substrate upon which a color filter is formed;
 - forming an alignment layer on one of the lower substrate and the upper substrate using an ink jet method; and
 - forming a plurality of spacers on one of the lower substrate and upper substrate.

12. The method according to claim 11, wherein the step of forming an alignment layer includes forming a plurality of holes that expose portions of one of the lower and upper substrates.

13. The method according to claim 12, wherein each of the plurality of spacers are formed within each of the plurality of holes.

14. The method according to claims 11, wherein the step of forming the plurality of spacers includes an ink jet method.

15. The method according to claim 11, further comprising:

applying a sealing material on the upper substrate; and

dispensing liquid crystal material onto the lower substrate.

16. A method of fabricating a liquid crystal display device, comprising:

providing a lower substrate upon which a thin film transistor is formed

and an upper substrate upon which a color filter is formed;

applying a first alignment layer along an entire surface of the lower

substrate using an ink jet method;

applying a second alignment layer along a surface of the upper substrate using the ink jet method, the second alignment layer having a plurality of holes that expose surface portions of the upper substrate; and

forming a spacer in each of the plurality of holes formed on the expose surface portions of the upper substrate using the ink jet method.

17. A method of fabricating a liquid crystal display device, comprising:

providing a first substrate and a second substrate;

dispensing a first alignment material on first surface portions of the first substrate to expose second surface portions of the first substrate; and

dispensing the first alignment material on second surface portions of the second substrate to expose second surface portions of the second substrate.

18. The method according to claim 17, wherein the first substrate is a color filter substrate and the second substrate is a thin film transistor substrate.

19. The method according to claim 17, wherein the steps of dispensing comprise:

locating nozzles at the exposed second surface portions of the first substrate and the exposed second surface portions of the second substrate; and

dispensing the first alignment material onto the exposed second surface portions of the first substrate and the exposed second surface portions of the second substrate.

20. The method according to claim 19, wherein the steps of dispensing include movement of the first substrate and movement of the second substrate.

21. The method according to claim 19, wherein the steps of dispensing include movement of the nozzles.